

Title (en)

Coating apparatus

Title (de)

Auftragsvorrichtung

Title (fr)

Dispositif d'enduction

Publication

EP 1555345 A3 20101215 (DE)

Application

EP 04105787 A 20041116

Priority

DE 10359114 A 20031217

Abstract (en)

[origin: EP1555345A2] The coating head (2), which includes the curtain nozzle (4), can be moved. It is rotated or displaced linearly. This causes the flowing curtain (5) to be intercepted (8'). In the new design the nozzle height (H c) is less than the interceptor rim height (H w) above the web. Seen in the running direction (L) of the surface (7), the curtain coating interceptor (8') is located immediately after the coating head. The coating head and curtain nozzle (4) can be rotated counter-clockwise, through preferably 45[deg]. An additional coating unit (10, 10'') is provided. The coating units are both fixed and moveable, and have both plane and sloping base surfaces (10a, 10a''). The interceptor has high side walls (8a) and is fixed to the curtain coating unit. Further variants of the basic arrangement are described.

IPC 8 full level

D21H 23/48 (2006.01); **B05C 5/00** (2006.01)

CPC (source: EP)

B05C 5/005 (2013.01); **D21H 23/48** (2013.01)

Citation (search report)

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- [A] DE 19903559 A1 19991021 - MITSUBISHI PAPER MILLS LTD [JP]
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Designated contracting state (EPC)

AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HU IE IS IT LI LU MC NL PL PT RO SE SI SK TR

Designated extension state (EPC)

AL HR LT LV MK YU

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EP 1555345 A2 20050720; EP 1555345 A3 20101215; DE 10359114 A1 20050721; DE 20321850 U1 20110303

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